

Fig. 1

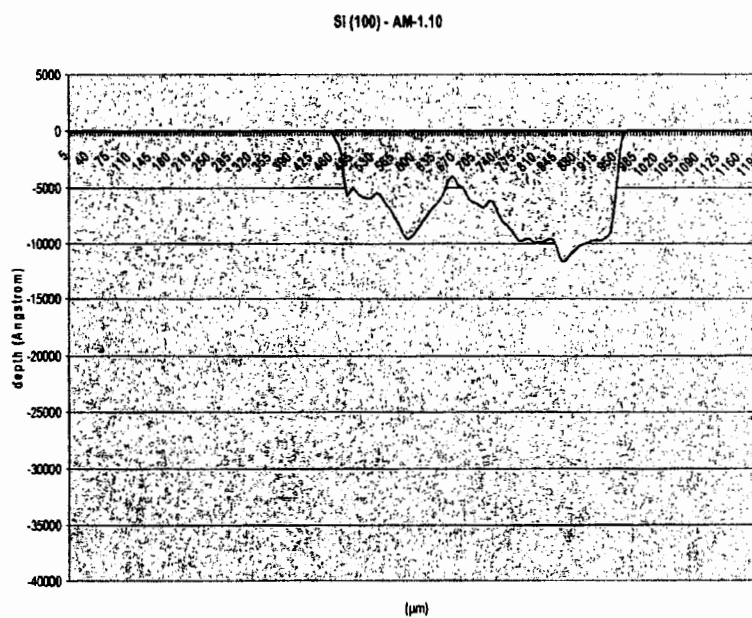


Fig. 2

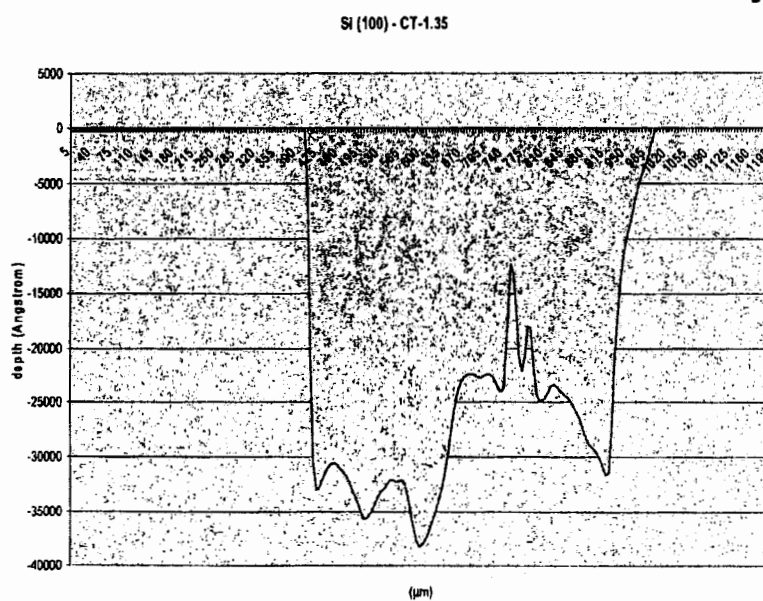
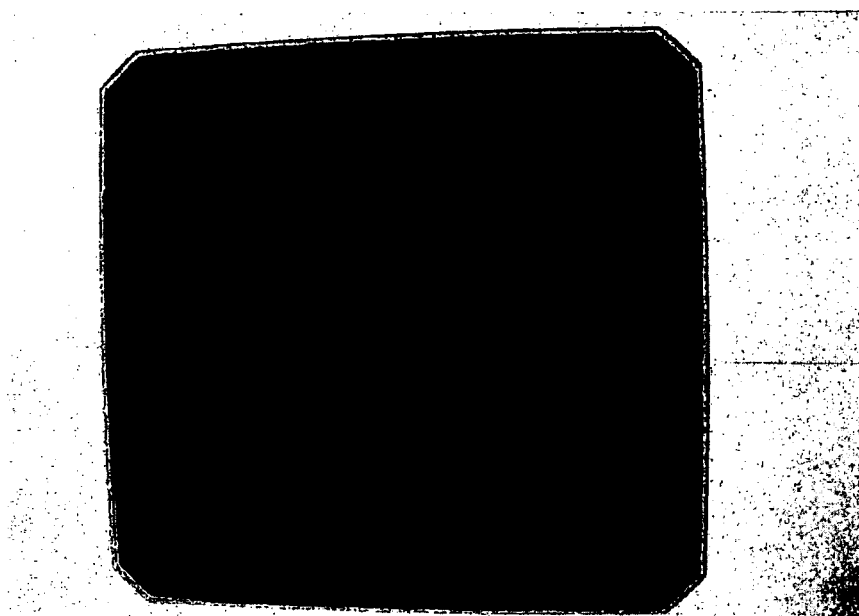
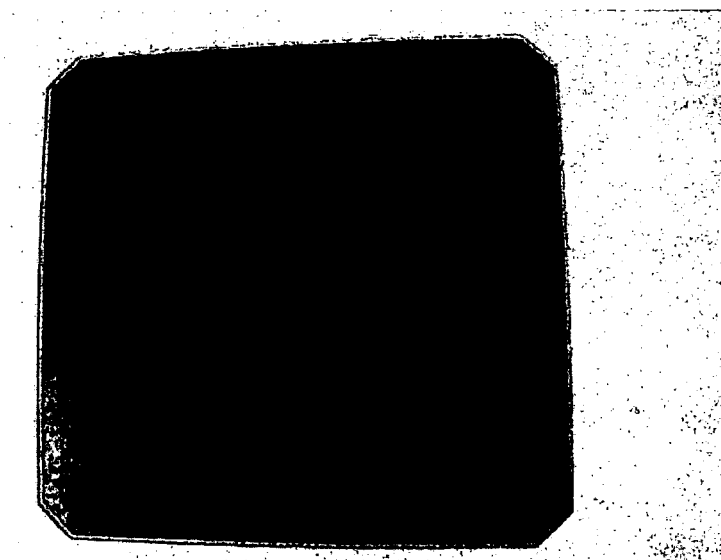


Fig. 3



C

Fig. 4



C

Fig. 5

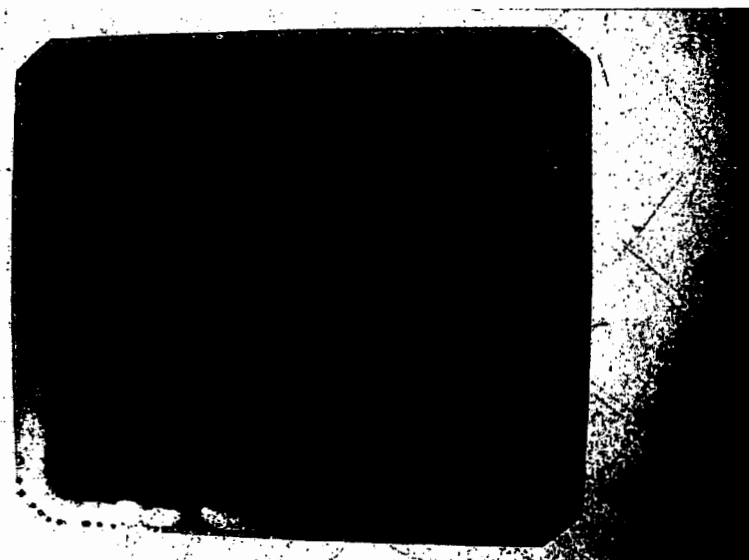


Fig. 6

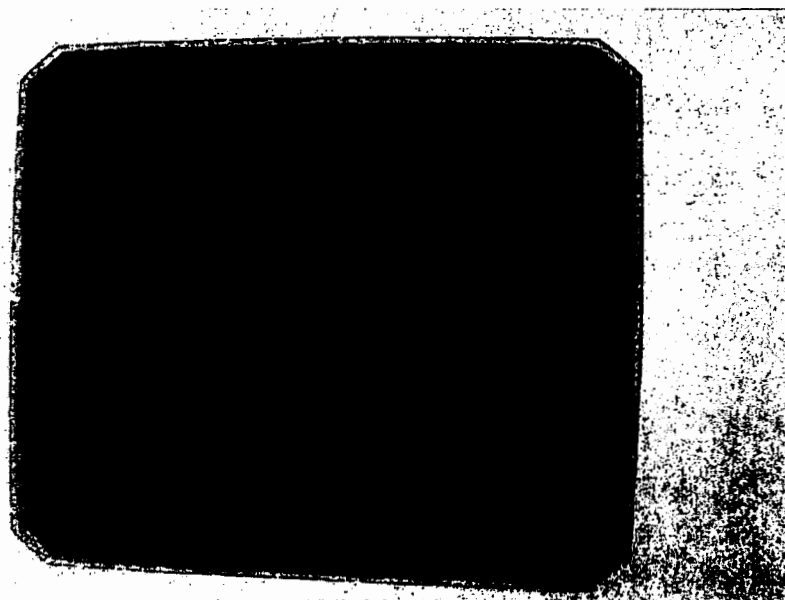


Fig. 7

Molten polymer sheath,
prevents paste liquefaction and paste spread after etching at room temperature on Si wafers

